

# Mapping and evaluation of visco-elastic properties on micro- and nanoscale by use of modified atomic force microscopy



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# Overview

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Elastic and viscoelastic interactions

Kelvin-Voigt model

Elastic and viscoelastic characterization of materials on macro- and micro-scale

How can we use AFM high resolution methods?

Principle of atomic force acoustic microscopy (AFAM)

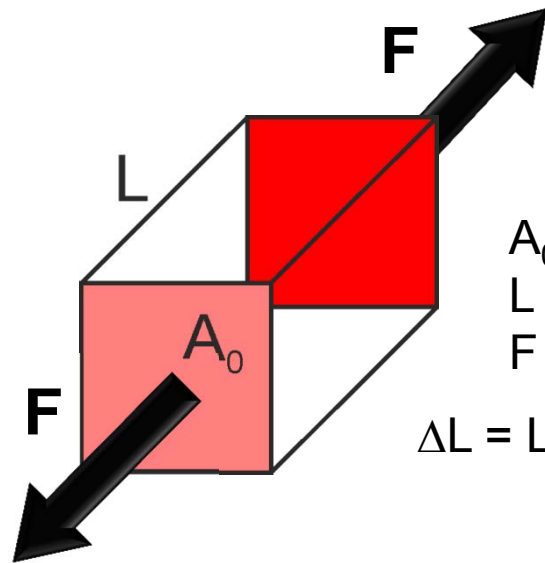
Tip-sample interactions, or where is the elastic and viscoelastic component?

What is also possible...



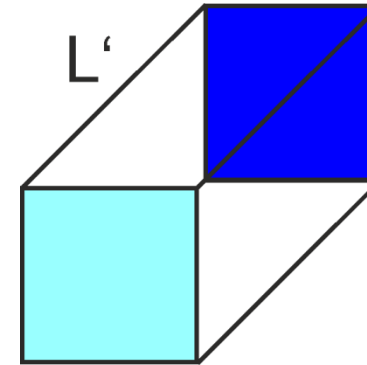
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# Elastic interaction



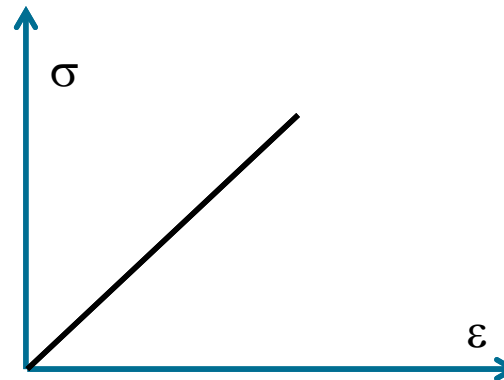
$A_0$  – surface area  
 $L$  – length of the element  
 $F$  – applied load (force)

$\Delta L = L' - L$  – change in the length



$$\sigma = \frac{F}{A_0} \text{ - applied stress;}$$

$$\varepsilon = \frac{\Delta L}{L} \text{ - resulting strain}$$



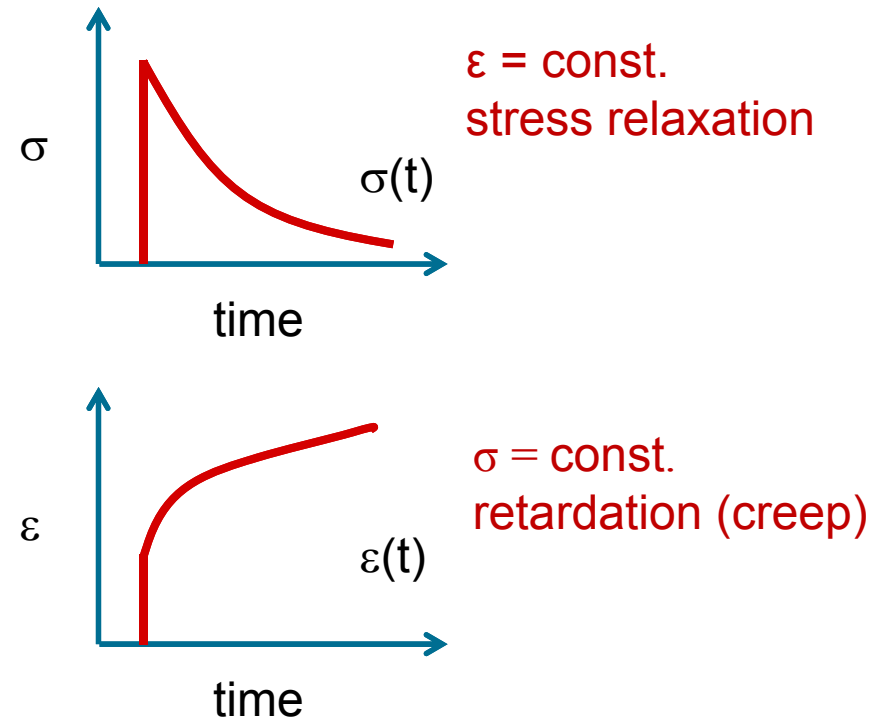
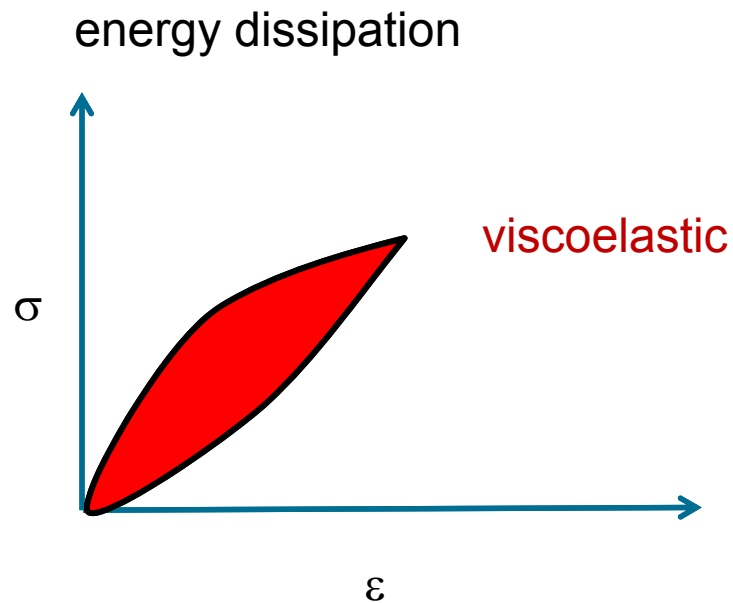
$$E = \frac{\sigma}{\varepsilon} \text{ - Young's modulus}$$

Elastic deformation is reversible

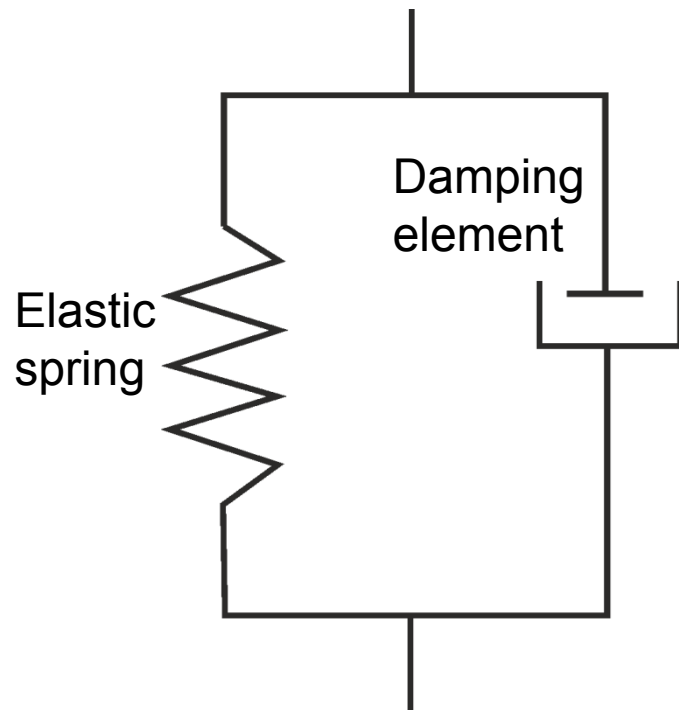
# Viscoelasticity

## Trademarks of viscoelasticity:

time dependence of material properties



# Kelvin-Voigt model



Kelvin-Voigt model describes the time dependence in the stress-strain change rate:

$$\sigma(t) = E\varepsilon(t) + \eta \frac{d\varepsilon(t)}{dt},$$

$\eta$  is the viscosity

Static methods:  $\varepsilon(t) = \frac{\sigma_0}{E} (1 - e^{-\lambda t})$ ,

where  $\lambda = \frac{E}{\eta}$  is rate of relaxation

Dynamic methods:  $E^{dyn}(\omega) = E' + iE''$ ,

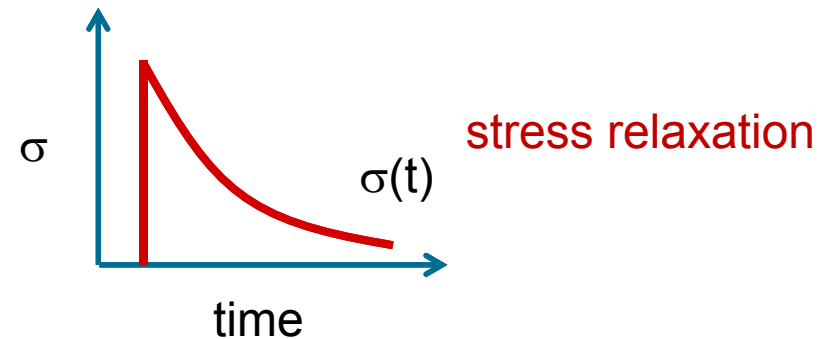
where  $E'$  and  $E''$  are the storage and loss moduli

# Methodology for bulk materials

Static testing methods:  
measurements of relaxation and retardation

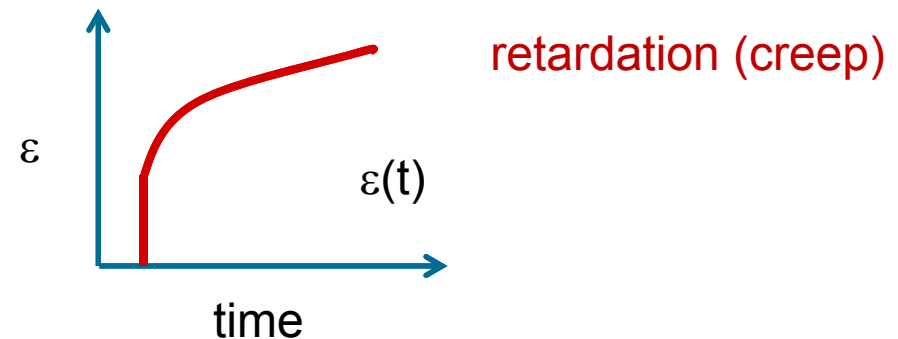
time dependent modulus of elasticity

$$E(t) = \frac{\sigma(t)}{\varepsilon_0}$$



time dependent compliance

$$C(t) = \frac{\varepsilon(t)}{\sigma_0}$$



# Methodology for bulk materials

## Dynamic-Mechanical analysis (DMA):

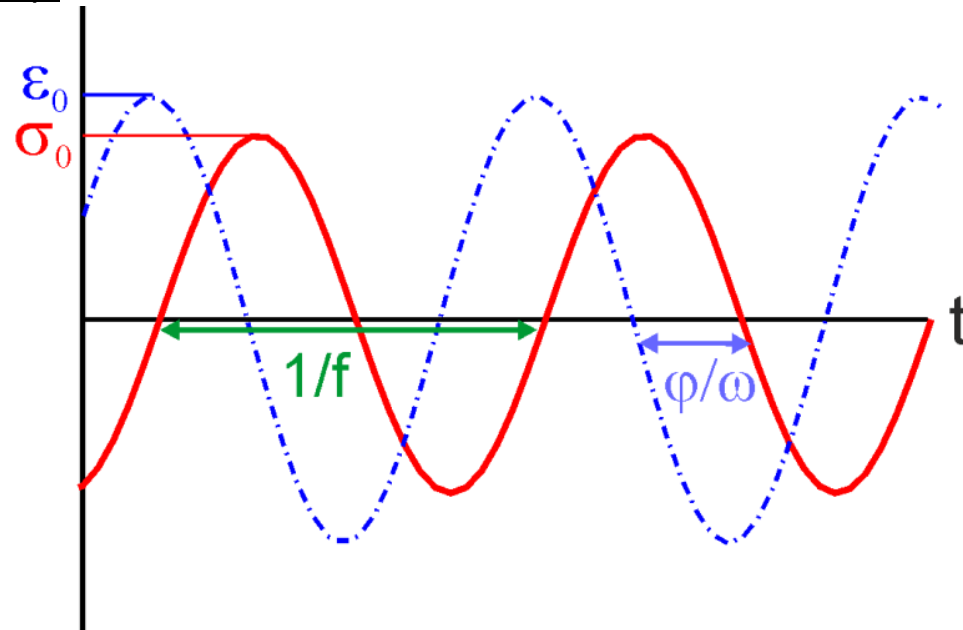
forced vibrations:

$$\varepsilon(t) = \varepsilon_0 \sin \omega t,$$

$$\sigma(t) = \sigma_0 \sin(\omega t + \varphi)$$

$$\text{storage modulus } E' = \frac{\sigma_0}{\varepsilon_0} \cos \varphi$$

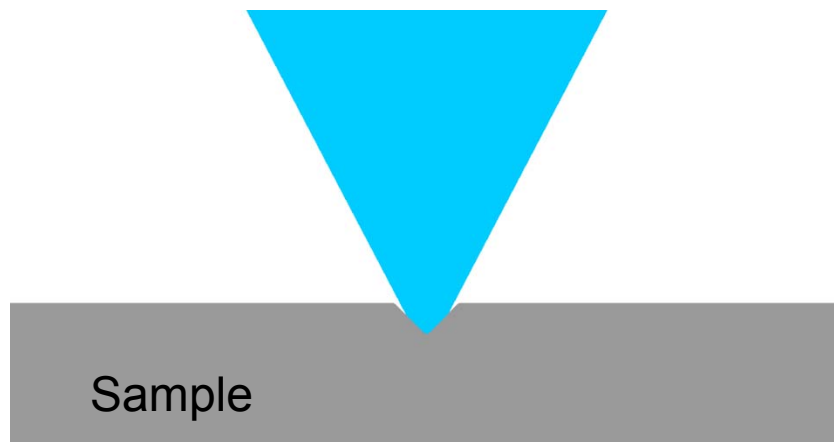
$$\text{loss modulus } E'' = \frac{\sigma_0}{\varepsilon_0} \sin \varphi$$



# What about thin film systems?

## Nanoindentation

Diamond indenter



Force range: 100 nN – several mN

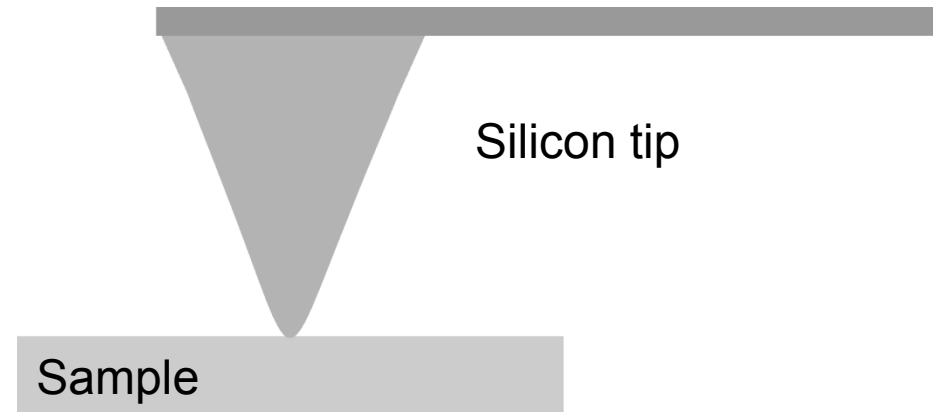
Tip radius: 100 nm – 500 nm - 20  $\mu$ m

Film thickness limit : ca. 200 nm

Indentation depth: 5 nm – 20  $\mu$ m

## AFM based methods

Silicon tip



Force range: 1 nN – several  $\mu$ N

Tip radius: 10 nm – 150 nm – 500 nm

Film thickness limit : ca. 50 nm



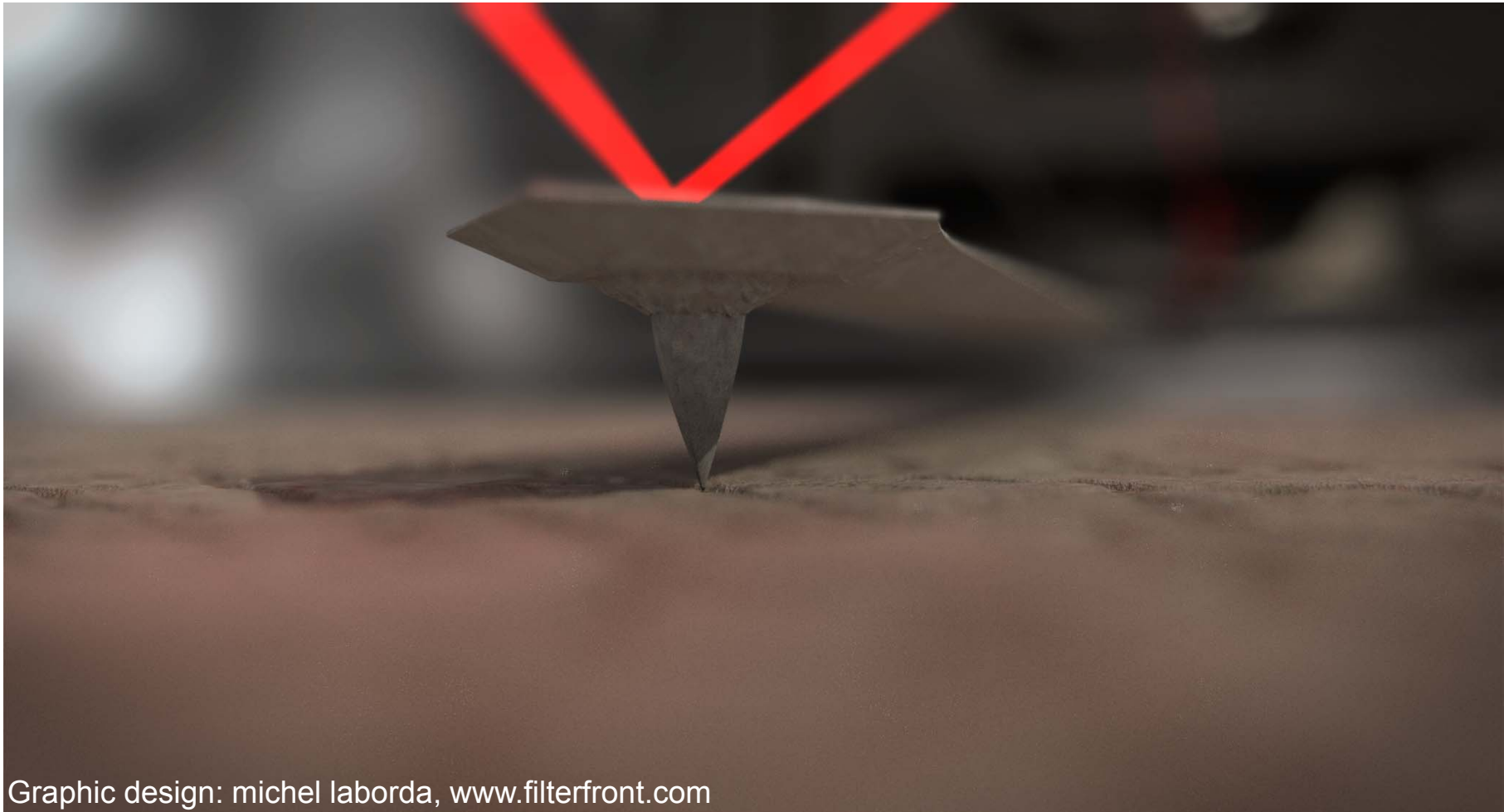
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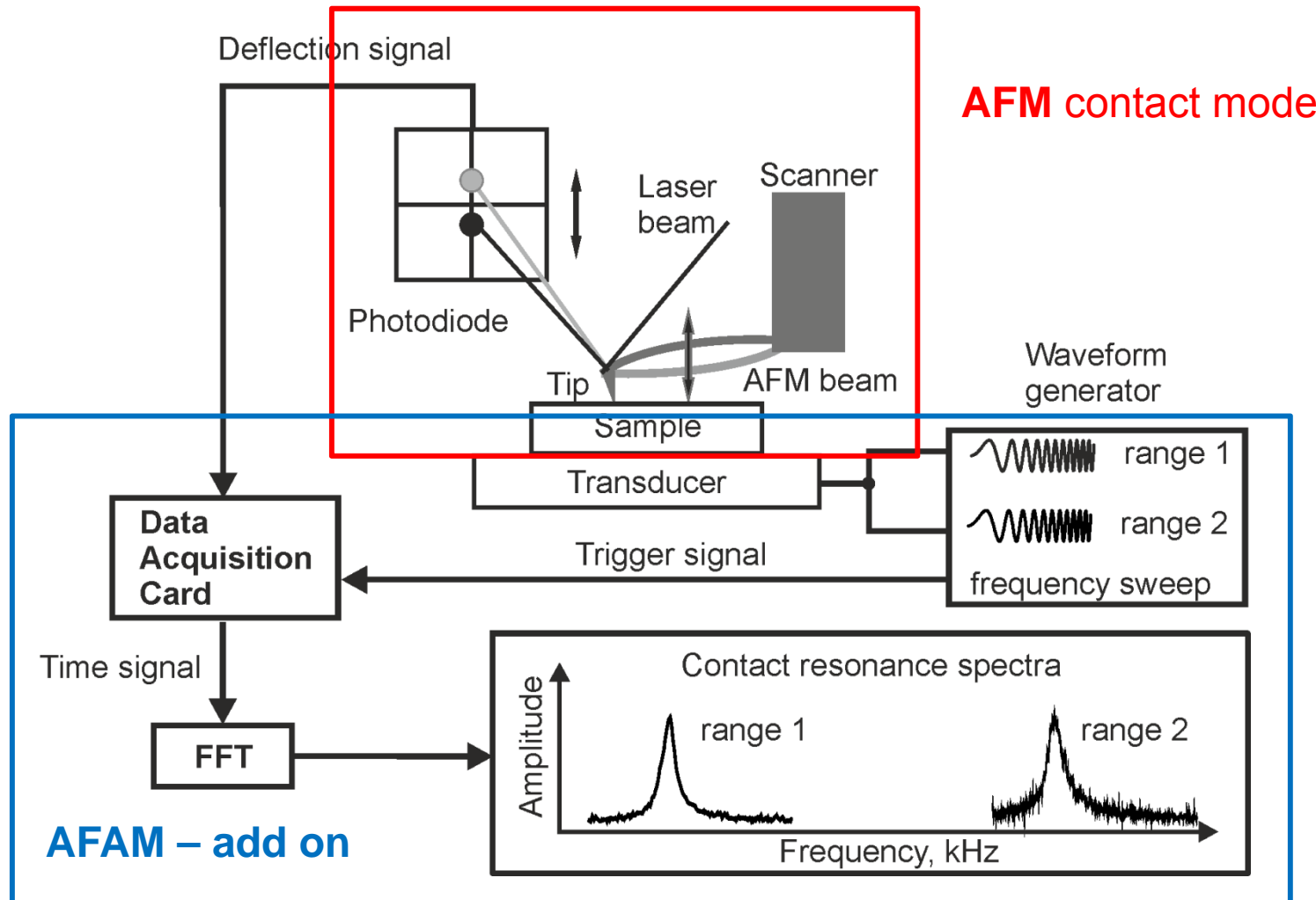
# AFM methods

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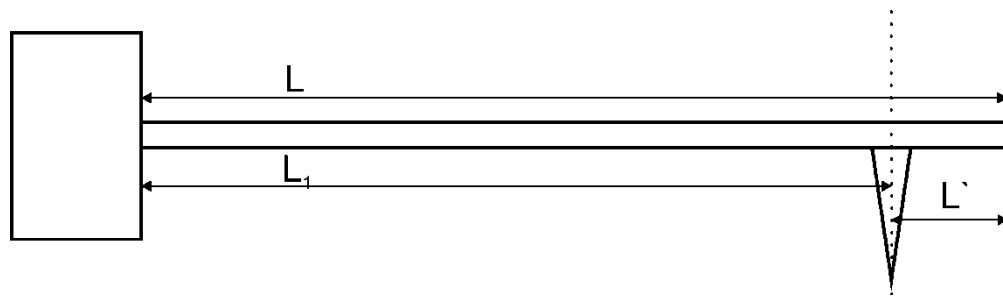


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# What is AFAM?



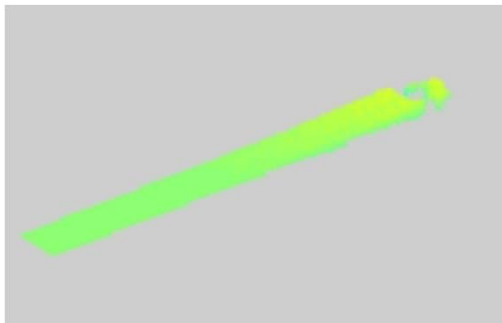
# Free resonance frequencies of an AFM cantilever



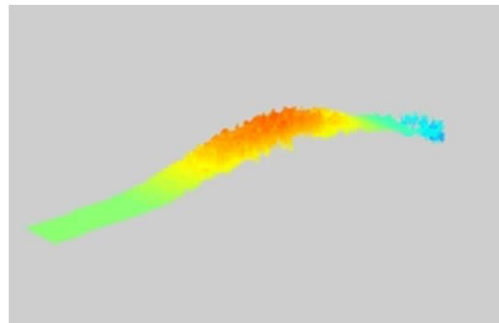
$$f_{free}^1 = 0.162 \sqrt{\frac{E}{\rho}} \frac{T}{L^2}$$

L – length  
T – thickness  
E – Young's modulus  
 $\rho$  – density

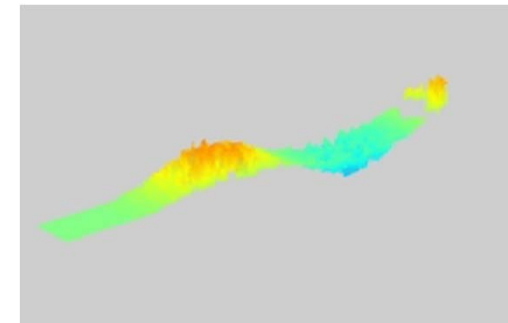
1<sup>st</sup> Mode  $f = 85.84$  kHz



2<sup>nd</sup> Mode  $f = 532.84$  kHz



3<sup>rd</sup> Mode  $f = 1486.1$  kHz

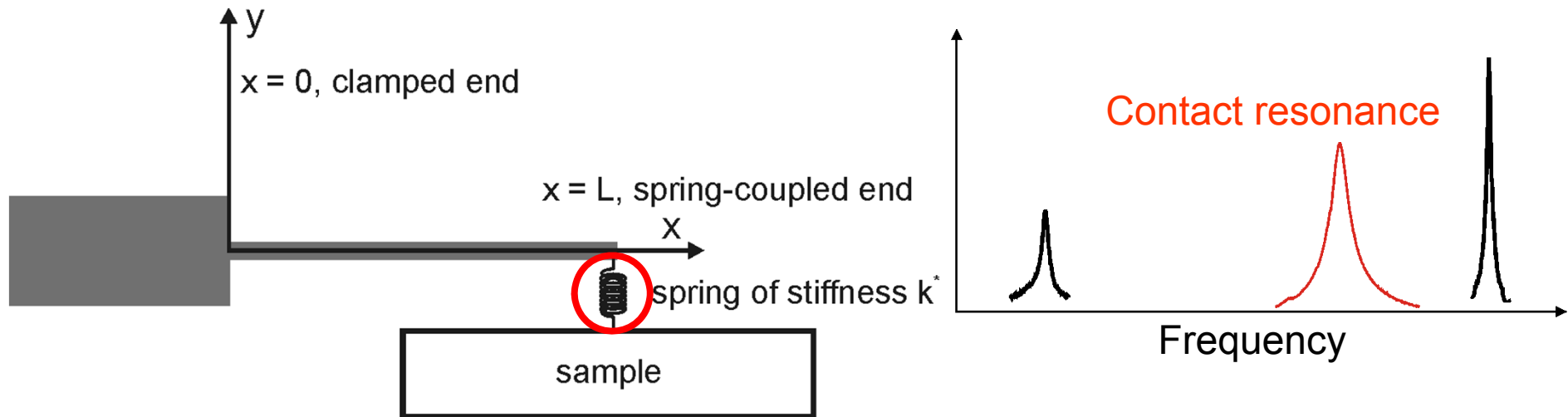


Cantilever vibrations measured at IZFP-Saarbrücken



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# Contact resonance frequencies of an AFM cantilever



dynamic behavior  
of the cantilever

Value of the contact  
resonance frequency  
 $f_n$

tip-sample contact stiffness

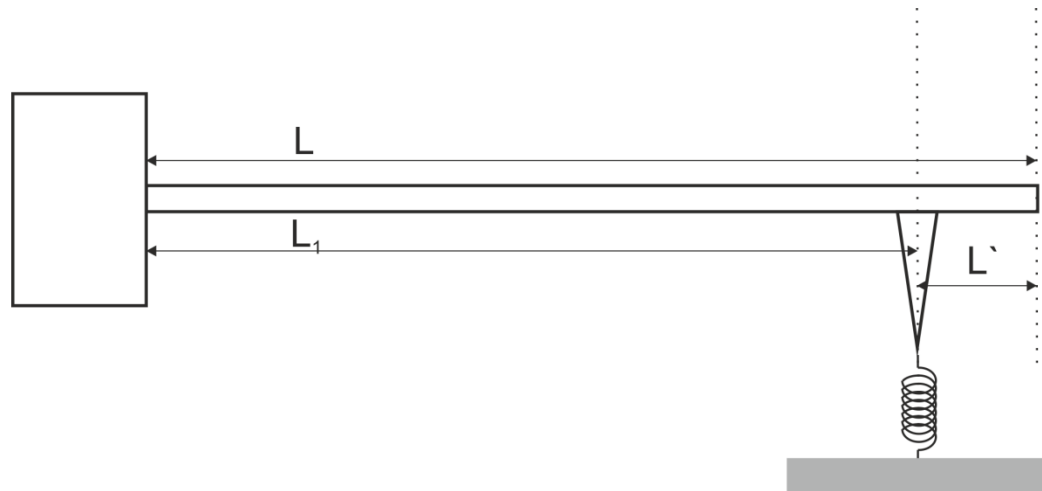
$k^*$

contact mechanics

$$k^* = 2aE^*$$

$$\frac{1}{E^*} = \frac{1}{M_{tip}} + \frac{1}{M_{sam}}$$

# Equations for $k^*$ – simple model for elastic interactions



$$L = L_1 + L'$$

$L_1/L$  – tip position parameter

Contact resonance frequency  $f_n$  is a function of:

geometry and mechanical properties of the beam – parameter  $\alpha$

Free resonance frequencies –  $f_{n(\text{free})}$

Tip-sample contact stiffness –  $k^*$

Tip-position parameter -  $L_1/L = r$

Spring constant -  $k_c$

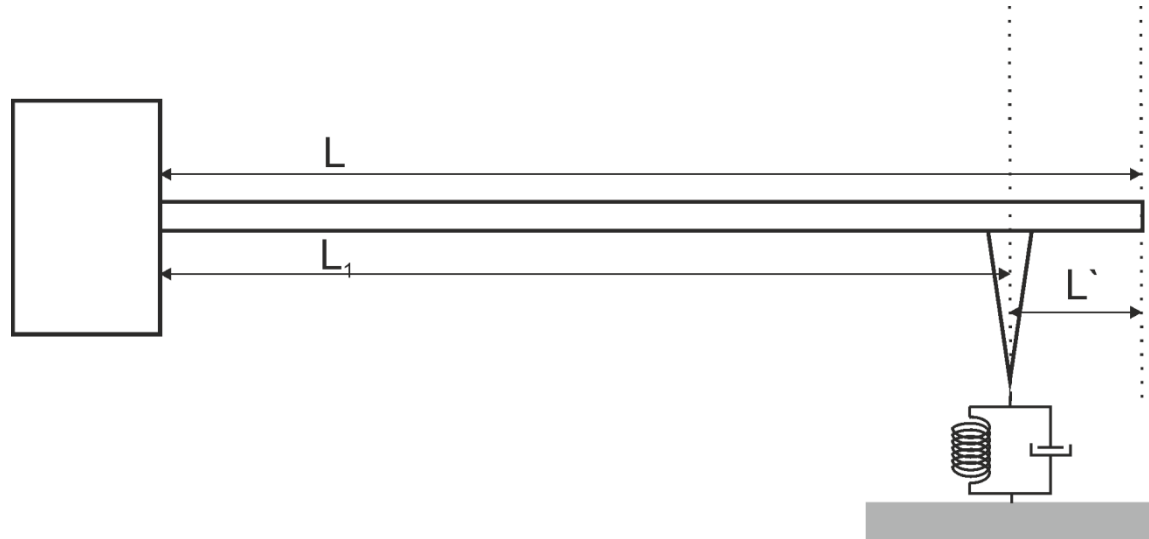
## Equations for $k^*$ – the simple model

$$\frac{k^*}{k_c} \left[ -(\cosh \alpha L r \sin \alpha L r - \sinh \alpha L r \cos \alpha L r) \right. \\ \times \left( 1 + \cos \alpha L (1-r) \cosh \alpha L (1-r) \right. \\ \left. + (\cosh \alpha L (1-r) \sin \alpha L (1-r)) - \sinh \alpha L (1-r) \cos \alpha L (1-r) \right) \times \\ \left. \times (1 - \cos \alpha L r \cosh \alpha L r) \right] = 2 \frac{(\alpha L r)^3}{3} (1 + \cos \alpha L \cosh \alpha L)$$

$$\alpha L = (\alpha_n L)_{free} \sqrt{\frac{f_{n(cont)}}{f_{n(free)}}}$$

n	$(\alpha_n L)_{free}$
1	1.87
2	4.69
3	7.88

# Equations for $k^*$ – simple model for viscoelastic interactions



Contact resonance frequency  $f_n$  is additionally a function of:

$\chi = \frac{2\pi f_{n0}}{Q_{n0}}$  – damping of the cantilever in air

$Q_{n0}$  – Q factor of the free resonance frequency

$Q_n$  – Q factor of the contact resonance frequency

## Equations for $k^*$ – simple model for viscoelastic interactions

$$\begin{aligned} & \left( k' + i\beta(\alpha L r)^2 \right) \left[ -(\cosh \alpha L r \sin \alpha L r - \sinh \alpha L r \cos \alpha L r) \right. \\ & \times \left( \begin{aligned} & 1 + \cos \alpha L(1-r) \cosh \alpha L(1-r) \\ & + (\cosh \alpha L(1-r) \sin \alpha L(1-r)) - \sinh \alpha L(1-r) \cos \alpha L(1-r) \end{aligned} \right) \times \\ & \left. \times (1 - \cos \alpha L r \cosh \alpha L r) \right] = 2 \frac{(\alpha L r)^3}{3} (1 + \cos \alpha L \cosh \alpha L) \end{aligned}$$

$$\alpha L = (\alpha_n L)_{free} \sqrt{\frac{f_{n(cont)}}{f_{n(free)}} \left( 1 + i \left( 2\pi f_{n(cont)} - \chi Q_{n(free)} / 8\pi f_{n(cont)} Q_{n(con)} \right) \right)}$$

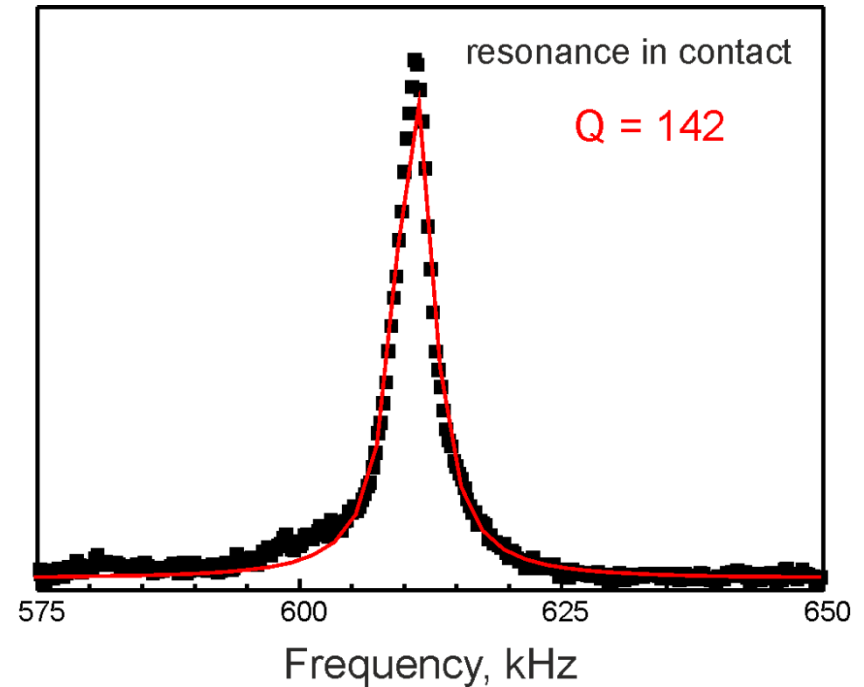
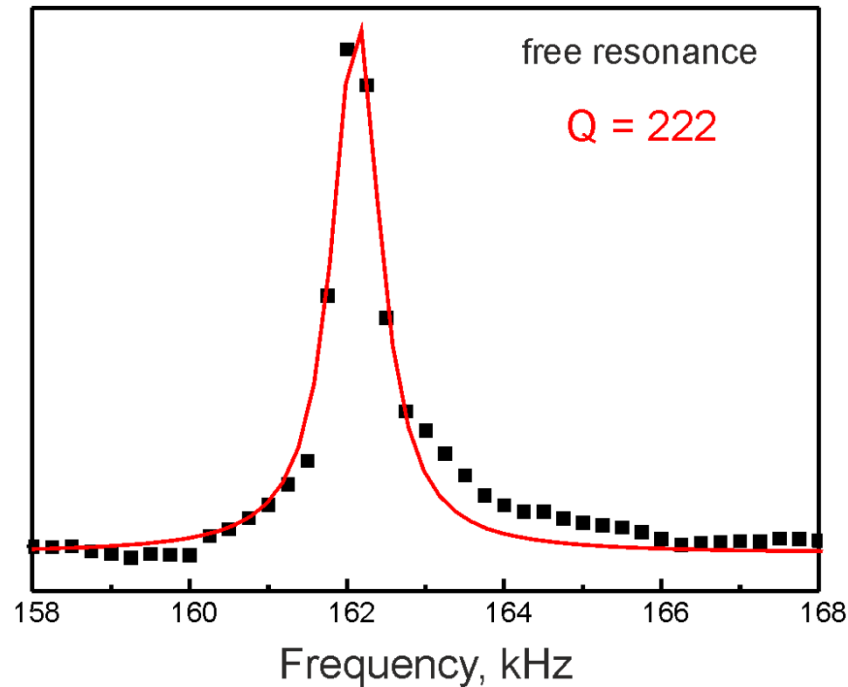
$k'$  is the normalized contact stiffness

$\beta$  is the damping constant

Source: D.C. Hurley, JAP, 2004, J. Killgore, Langumuir, 2011



# Q-factor



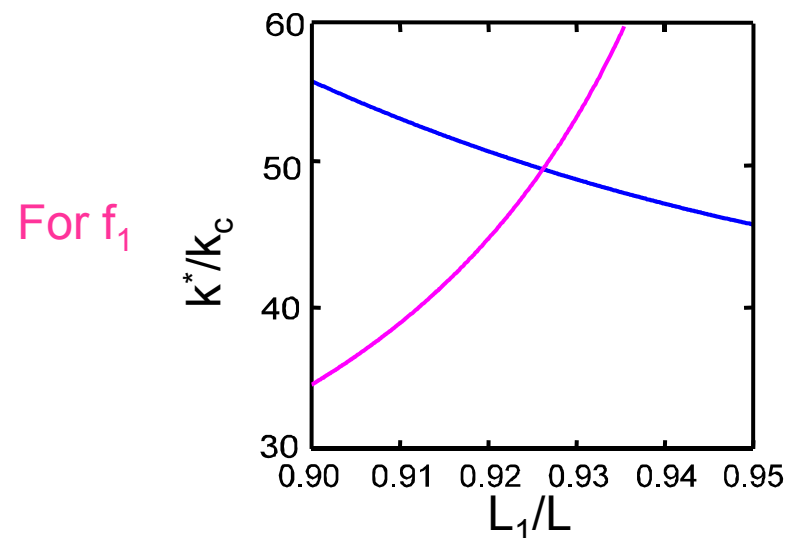
From the analysis of the resonance spectrum we can determine values of the contact resonance frequencies, Q factor, and damping of the cantilever in air

## Determination of $k^*$ from the contact resonance frequencies

$k^*$  - tip-sample contact stiffness = ?

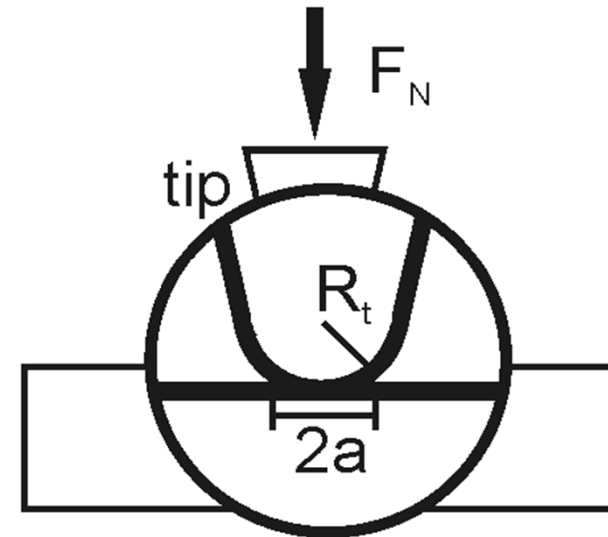
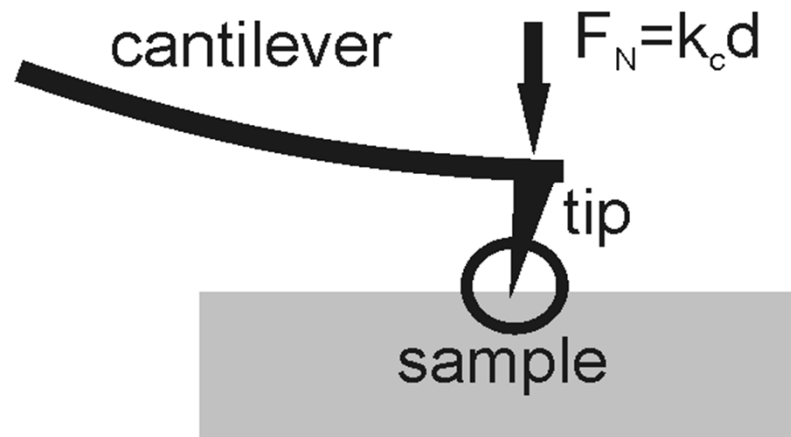
$r$  – tip position parameter = ?

We can calculate the values of  $k^*$  as a function of tip position parameter for a given value of the contact resonance frequency measured with the AFAM system



We have to measure the contact resonance frequencies for at least two modes!

## Contact mechanics



$k^*$  - contact stiffness

$a$  – contact radius

$E^*$  - reduced Young's modulus

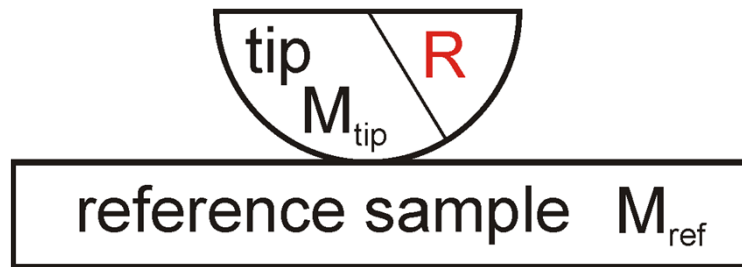
$R$  – tip radius

$F$  – static load

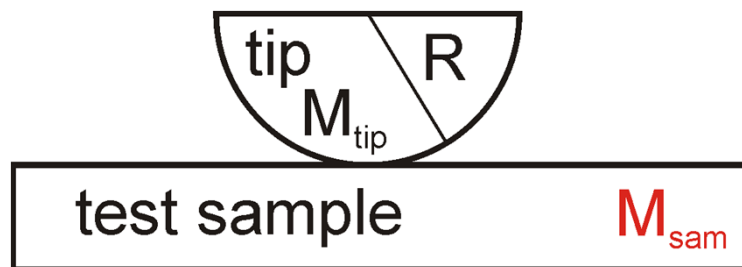
$$a = \sqrt[3]{\frac{3RF}{4E^*}}$$

$$k^* = \sqrt[3]{6RFE^{*2}}$$

## How to calculate the indentation modulus M?



$$\rightarrow k_{ref}^* = \sqrt[3]{6RFE_{ref}^{*2}}$$



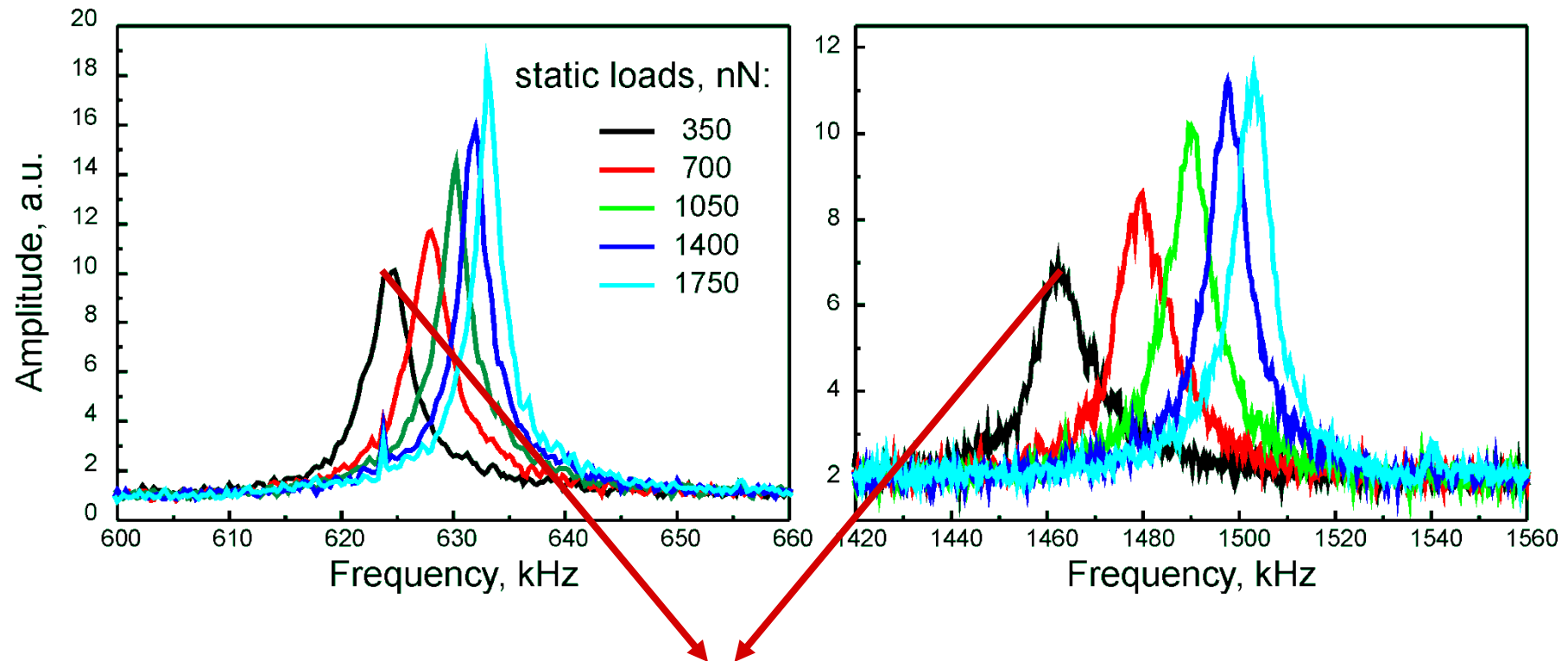
$$\rightarrow k_{sam}^* = \sqrt[3]{6RFE_{sam}^{*2}}$$

$$E_{sam}^* = E_{ref}^* \left( \frac{k_{sam}^*}{k_{ref}^*} \right)^{3/2}$$

$$M_{sam} = \left( \frac{1}{E_{sam}^*} - \frac{1}{M_{tip}} \right)^{-1}$$

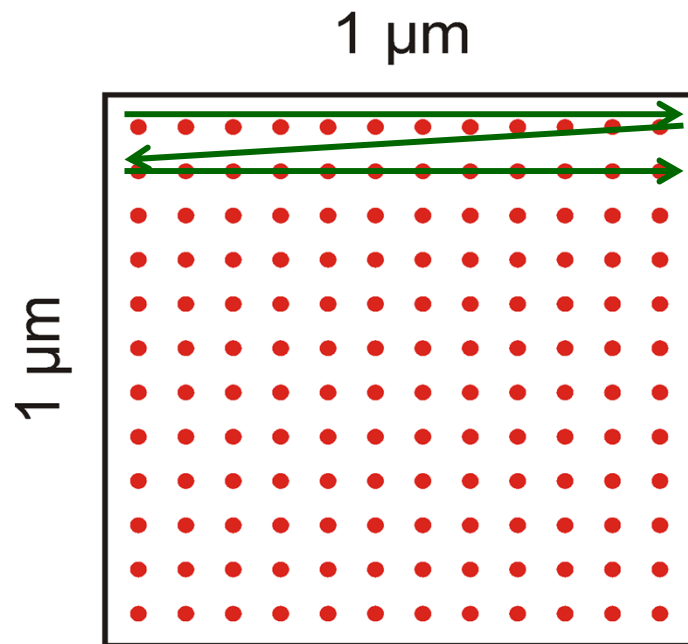
## Spectroscopy mode: single point measurements

Contact resonance spectra acquired on Si (100) sample



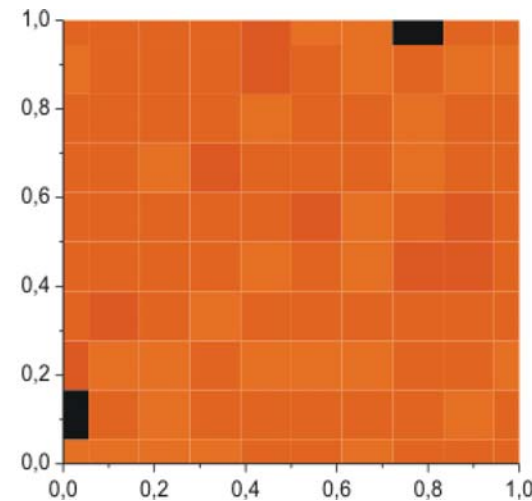
We use the values of the contact resonance frequencies to calculate  $k^*$

# Principle of the grid measurement



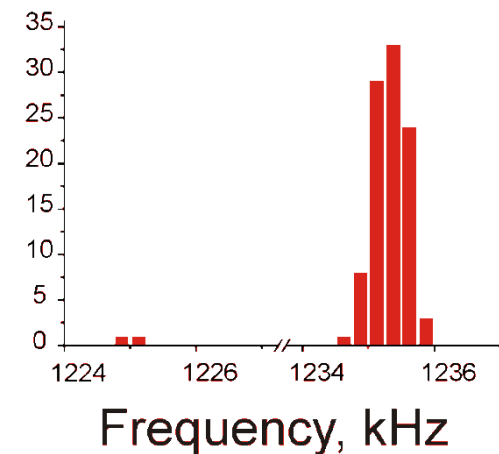
The values of contact resonance frequencies are determined as a function of a position on the sample surface at a fixed value of the applied static load.

The results can be presented ...

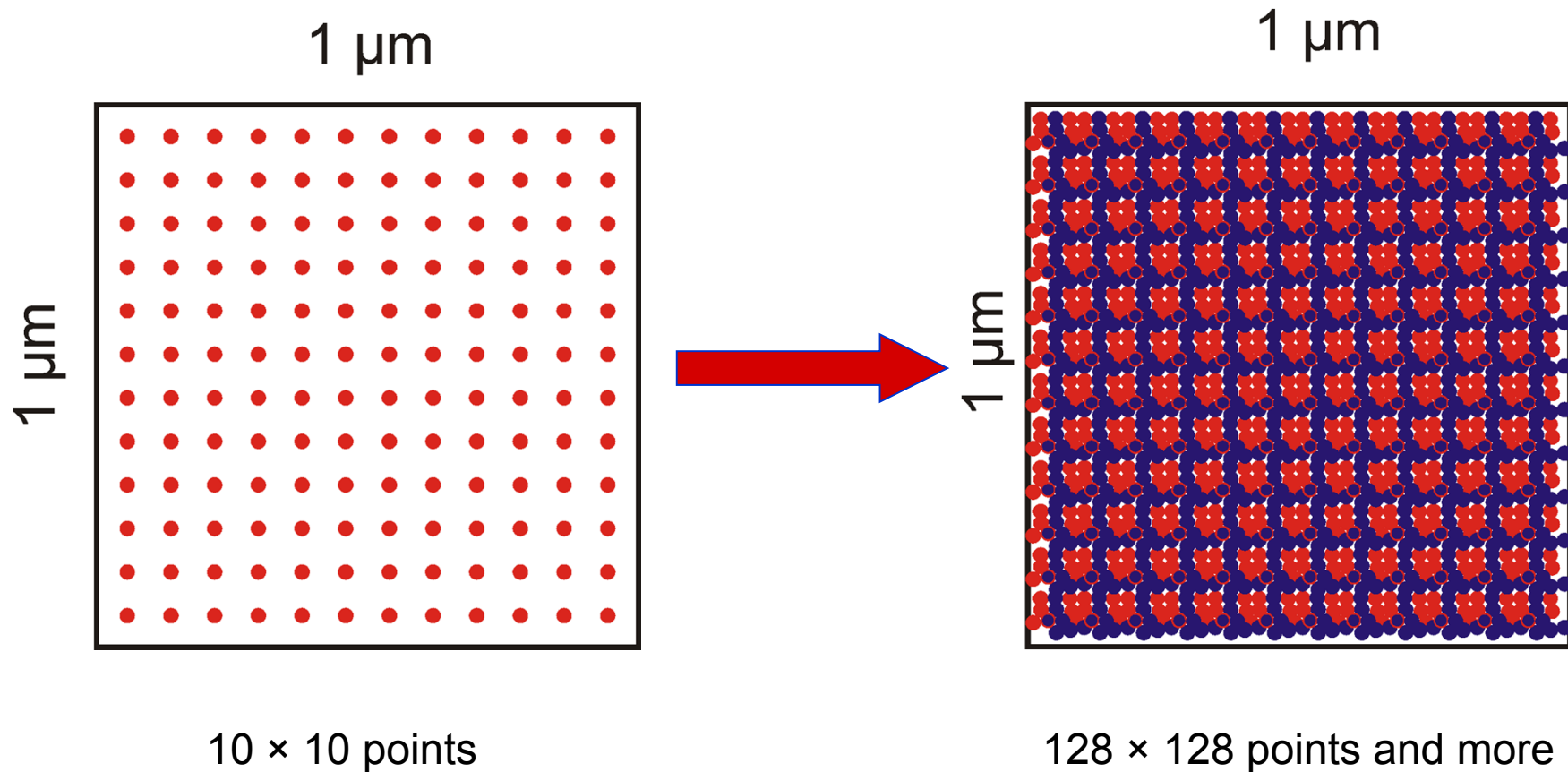


...as grids....

...or histograms.



## And for inhomogeneous samples...



## In the near future

### AFAM Dynamic-Mechanical analysis (DMA):

forced vibrations:

$$F(t) = F_0 \sin \omega t$$

Determine  $k^*$ ,  $\epsilon$ ,  $\sigma$  and calculate

$$\text{storage modulus } E' = \frac{\sigma_0}{\epsilon_0} \cos \varphi$$

$$\text{loss modulus } E'' = \frac{\sigma_0}{\epsilon_0} \sin \varphi$$

